

Abstract

Provided are an inspection system and a temperature control method with which a substrate is inspected while temperature control is suitably performed.

5 The inspection system inspects a substrate while performing temperature control by a temperature adjustment mechanism. The inspection system comprises: a substrate holding unit that holds the substrate; a detection unit that supplies an inspection power to an electrode of the substrate; and a control unit. The detection unit has a temperature estimation unit that estimates a bonding portion

10 temperature of a bonding portion provided to the substrate. The control unit includes: a step for supplying the inspection power to the substrate; a step for obtaining information related to the bonding portion temperature after the supply of the inspection power has been stopped; a step for determining an offset temperature of the substrate holding unit on the basis of the information related to

15 the bonding portion temperature; a step for adjusting the temperature of the substrate holding unit on the basis of a control temperature offset by the offset temperature; and a step for supplying the inspection power to the substrate after the temperature of the substrate holding unit has been adjusted, and inspecting the substrate.